



## ISC Audits & Reviews SC Summary (May 15th, 2026)

Doc.	Title	Results
6570D;	New Standard: Guide for Measuring Bulk Micro Defect Density and Denuded Zone Width in Annealed Silicon Wafers by a Laser Scattering Tomography Technique;	Passed
7111;	Revision of SEMI M81-0418, Guide for Defects Found in Monocrystalline Silicon Carbide Substrates;	Passed
7383;	Reapproval of SEMI D20-0706 (Reapproved 0221), Terminology for FPD Mask Defect;	Passed
7384;	Reapproval of SEMI D21-0706 (Reapproved 0221), Terminology for FPD Mask Pattern Accuracy;	Passed
7385-LI1;	Add 5.1.2 to Section 5 to describe Smart Contract.;	Passed
7385-LI2;	To add a Blockchain Implementation Overview to Section 6, add 6.3, 6.3.1, 6.3.2, 6.3.3, and 6.3.4.;	Passed
7385-LI3;	Add 6.4, 6.4.1, and 6.4.2 to Section 6 to describe Blockchain Configuration.;	Passed
7385-LI4;	Add 6.5, 6.5.1, 6.5.2, and 6.5.3 to Section 6 to describe the Blockchain Function.;	Passed
7385-LI5;	Add 6.6 and 6.6.1 to Section 6 to describe Smart Contract.;	Passed
7385-LI6;	Add 6.7, 6.7.1 and 6.7.2 to Section 6 to describe Security.;	Passed
7385-LI7;	Add R2, R2-1, R2-1.1, R2-1.2, R2-1.3, R2-1.4, and R2-1.5 to describe traceability examples in RELATED INFORMATION and add Figure R2-1 to illustrate the Traceability example.;	Passed
7398;	<b>New Standard: Test Method For Wafer Bond Strength Measurement By Double Cantilever Beam;</b>	<b>Failed</b>
7403;	Revision to SEMI D53-0421, Specification For Flat Panel Display (FPD) Pellicles;	Passed
7404-LI1;	Obsolete and unnecessary references are removed.;	Passed
7412;	Reapproval of SEMI D42-0421, Specification for Ultra Large Size Mask Substrate Case;	Passed
7413;	Revision to SEMI D80-0421, with title change from Test Method for Measurement of Water Vapor Transmission Rate for High Gas Barrier Plastic Film in a Short Time to Test Method for Measurement of Water Vapor Transmission Rate for High Gas Barrier Plastic Films Using a Quadrupole Mass Spectrometer;	Passed
7416;	Reapproval of SEMI M82-0820 Test Method for the Carbon Acceptor Concentration In Semi-Insulating Gallium Arsenide Single Crystals By Infrared Absorption Spectroscopy;	Passed
R7086A;	Ratification Ballot, Revision to SEMI F61-0521, Guide for Design and Operation of a Semiconductor Ultrapure Water System, with title change to: Guide for Design, Construction, Installation, and Operation of a Semiconductor Ultrapure Water System	Passed
R7332;	Ratification Ballot, New Standard: Specification for Large JEDEC™ Tray Stack Loadport;	Passed

For more information, please contact the SEMI Standards Engineer/Coordinator.  
<http://www.semi.org/standards/contacts> ) nearest you.

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